

PROCEEDINGS OF SPIE

Advances in X-Ray/EUV Optics and Components XIX

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Editors

**19–20 August 2024
San Diego, California, United States**

Sponsored and Published by
SPIE

Volume 13150

Proceedings of SPIE 0277-786X, V. 13150

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Please use the following format to cite material from these proceedings:

Author(s), "Title of Paper," in *Advances in X-Ray/EUV Optics and Components XIX*, edited by Christian Morawe, Hidekazu Mimura, Ali M. Khounsary, Proc. of SPIE 13150, Seven-digit Article CID Number (DD/MM/YYYY); (DOI URL).

ISSN: 0277-786X

ISSN: 1996-756X (electronic)

ISBN: 9781510679603

ISBN: 9781510679610 (electronic)

Published by

SPIE

P.O. Box 10, Bellingham, Washington 98227-0010 USA

Telephone +1 360 676 3290 (Pacific Time)

SPIE.org

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